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INFORMATION

Applicant : Horacio D. Espinosa et al.

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DISCLOSURE

Serial No.: 10/801 928

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U.S. PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Name	Class	Sub Class	Filing Date

FOREIGN PATENT DOCUMENTS

Examiner Initial*	Document Number	Date	Country	Class	Sub Class	Translation Y/N

OTHER DOCUMENTS (Including Author, Title, Date, Pages, Etc.)

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AI	Piner, R. et al., "'Dip-Pen' Nanolithography," Science 283, Jan 1999, p. 661-663.
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AN	Zhang, M. et al., "A MEMS nanoplottter with high-density parallel dip-pen nanolithography probe arrays," Nanotechnology 13, 2002, p. 212-217.
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